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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): T. USUI, et al

Serial No.: 09/788,629

Filed: February 16, 2001

For: PROCESS MONITORING METHODS IN A PLASMA  
PROCESSING APPARATUS, MONITORING UNITS, AND A  
SAMPLE PROCESSING METHOD USING THE MONITORING  
UNITS

Group: 2812

Examiner:

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**PRELIMINARY AMENDMENT**

Commissioner for Patents  
Washington, D.C. 20231

August 14, 2001

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

**IN THE SPECIFICATION:**

Please replace the original specification with the attached Substitute Specification.

**IN THE CLAIMS:**

Please amend claims 6-14 as follows:

6. (amended) A potential difference and current measuring method as set forth in Claim 1, 2 or 5, wherein said potential difference and current measuring method is

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